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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant(s): George D. Papasouliotis; Robert D. Tas; Patrick A. Van Cleemput; Bart van Schravendijk  
Assignee: Novellus Systems, Inc.  
Title: PROCESS FOR DEPOSITING F-DOPED SILICA GLASS IN HIGH ASPECT RATIO STRUCTURES  
Serial No.: 10/035,773 Filed: December 21, 2001  
Examiner: Unassigned Group Art Unit: 1745  
Docket No.: M-5091-2P US

Newport Beach, California  
March 4, 2002

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Sir:

Please direct all correspondence in the above-identified application and with respect to any patent that issues on this application to the undersigned at this address:

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Sandy Kim

3/4/02

Date of Signature

Respectfully submitted,



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